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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Alan P. Sheng et al.
Serial No: 10/730,863
Confirmation No: 3529
Filed: December 8, 2003
For: SYSTEM AND METHOD FOR MULTI-WAFER SCANNING IN
ION IMPLANTERS
Examiner: Jack I. Berman
Art Unit: 2881

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the 23rd day of August, 2005.


Mark Superko

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

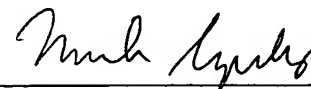
Petition for Extension of Time

A three-month extension of time to August 23, 2005 is requested for response to the Office Action of February 23, 2005.

The extension fee of \$1020.00 may be charged to deposit account No. 50-0896. If the amount is insufficient, please charge deposit account No. 50-0896. A duplicate of this Petition is enclosed.

Respectfully submitted,
Alan P. Sheng et al., Applicants

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